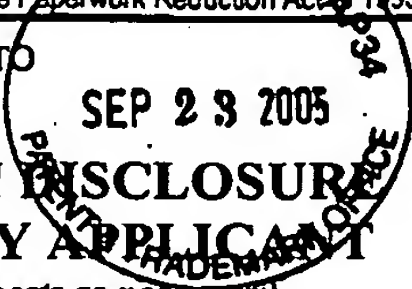
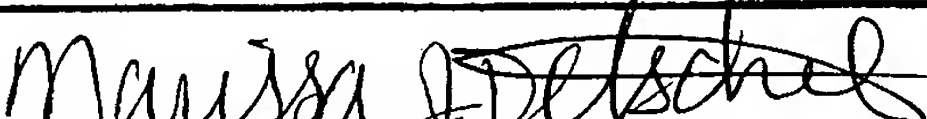


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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)		Complete if Known	
Application Number		10/651,049	
Filing Date		August 29, 2003	
First Named Inventor		Richard A. Gontin	
Art Unit		2877	
Examiner Name		Detschel, Marissa	
Attorney Docket Number		1857.2080000	
Sheet	1	of	2

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
mjd	US1	5,486,950	01/1996	Collinge	
mjd	US2	5,641,593	06/1997	Watanabe <i>et al.</i>	
mjd	US3	5,958,629	09/1999	Yan <i>et al.</i>	
mjd	US4	6,057,082	05/2000	Korth	
mjd	US5	6,072,631	06/2000	Guenther <i>et al.</i>	
mjd	US6	6,163,405	12/2000	Chang <i>et al.</i>	
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mjd	US12	US 2002-0122162 A1	9/2002	Nakauchi <i>et al.</i>	
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Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ¹ Number ⁴ Kind Code ⁵ (if known)				
mjd	FP1	EP 1 106 972 A1	06/2001	Henshaw		
mjd	FP2	EP 1 197 803 A2 & A3	04/2002	Van Elp <i>et al.</i>		
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mjd	FP4	JP 2000-266914	09/2000	Toshitaka		
mjd	FP5	EP 1 231 514 A1	08/2002	ASML Netherlands B.V.		
	FP6					
	FP7					
	FP8					
	FP9					

Examiner Signature		Date Considered	9-27-05
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Substitute for form 1449/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(Use as many sheets as necessary)</i>				Complete if Known	
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				Examiner Name	Detschel, Marissa
Sheet	2	of	2	Attorney Docket Number	1857.2080000

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		Number-Kind Code ² (if known)			
MJS MJS	US21	4,413,909	11-08-1993	Pohle	
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	US32				
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	US36				
	US37				
	US38				
	US39				
	US40				

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	FP10				
	FP11				
	FP12				
	FP13				
	FP14				
	FP15				
	FP16				
	FP17				
	FP18				

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Examiner Signature	Marissa G. Detschel	Date Considered	9-27-05
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		Filing Date	August 29, 2003
		First Named Inventor	Richard A. Gontin
		Art Unit	2877
		Examiner Name	Detschel, Marissa
Sheet 1 of 2	Attorney Docket Number	1857.2080000	

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume issue number(s), publisher, city and/or country where published	T ²
mgd	NPL1	Bjorkholm, J. E., "EUV Lithography - The Successor to Optical Lithography?", Intel Technology Journal Q3'98, 1998, pp. 1-8.	
mgd	NPL2	Goldberg, K.A., et al., "Extreme ultraviolet interferometry: at-wavelength testing of optics for lithography," The Advanced Light Source, 1998, at http://www-als.lbl.gov/als/compendium/AbstractManager/uploads/ACF4B6D.pdf , 4 pages.	
mgd	NPL3	Goldberg, K.A., et al., "Extreme ultraviolet interferometry: measuring EUV optical systems with sub-Å accuracy," The Advanced Light Source, 2001, at http://www-als.lbl.gov/als/compendium/AbstractManager/uploads/01125.pdf , 3 pages.	
mgd	NPL4	Kolb, R., "EUV Lithography Making Possible Next Generation of Semiconductors," Sciencebeat [online], June 5, 2001, at http://www.lbl.gov/Science-Articles/Archive/euv_milestone.html (visited January 12, 2003), 4 pages.	
mgd	NPL5	Lee, S. H., <i>High Accuracy EUV Interferometry</i> , at http://buffy.eecs.berkeley.edu/IRO/Summary/99abstracts/shlee.1.html (visited January 12, 2003), 1 page.	
mgd	NPL6	Mansuripur, M., "The Ronchi Test," MM Research, Inc., at http://www.mmresearch.com/articles/article1 (visited January 9, 2003), 12 pages (also published in <i>Optics & Photonics News</i> , July 1997, pp.42-46).	
mgd	NPL7	<i>Measurement Science in the Extreme Ultraviolet: Testing Advance Optics for Printing Integrated Circuits</i> , at http://www.als.lbl.gov/als/actrep/FileH.pdf (visited January 12, 2003), 2 pages.	
mgd	NPL8	Naulleau, P. P., et al., "Fabrication of high-efficiency multilayer-coated binary blazed gratings in the EUV regime," <i>Optics Communications</i> , Vol. 200, December 15, 2001, Elsevier Science B.V., pp. 27-34.	
mgd	NPL9	Wyant, J. C., "White Light Extended Source Shearing Interferometer," <i>Applied Optics</i> , Vol. 13, No. 1, January 1974, pp. 200-202.	
mgd	NPL10	Search Report from the European Patent Office for European Patent Application No. 04000512.6-2217, mailed January 3, 2005 (3 pages).	

Examiner Signature	Marissa Detschel	Date Considered	9-27-05
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Sheet	2	of	2	Attorney Docket Number	1857.2080000

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mgd	NPL11	Search Report from the Danish Patent and Trademark Office for Singapore Patent Application No. 200400112-9, mailed August 20, 2004 (7 pages).	
mgd	NPL12	English-language abstract for Japanese Patent Application No. 2000-266914, published September 29, 2000, from www.espacenet.com, 1 page.	
mgd	NPL13	Copy of the Search Report for Singapore Application No. 200400111-1, issued on June 5, 2004.	
	NPL14		
	NPL15		
	NPL16		
	NPL17		
	NPL18		
	NPL19		
	NPL20		

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Examiner Signature	Marissa J. Detschel	Date Considered	9-27-05
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